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## Scanning Electron Microscopy

- FEI Apreo C Low-Vac
- FEI SCIOS Dual-Beam SEM/FIB

## Capabilities

- Low Vac imaging of non-conductive samples
- Sectioning with Focused Ion Beam
- Elemental Analysis (EDX)
- EBSD
- E-beam Lithography
- STEM

## Other Instrumentation

- XRD
- DSC/TGA
- AFM
- TEM
- DLS

